

patented
VACUUM-HOLDER PLUS G

Our patented Wafer Holder PLUS G with easy exchangeable sealing lips, is a new generation of holding device. Created for electroplating of silicon wafers or other substrates.

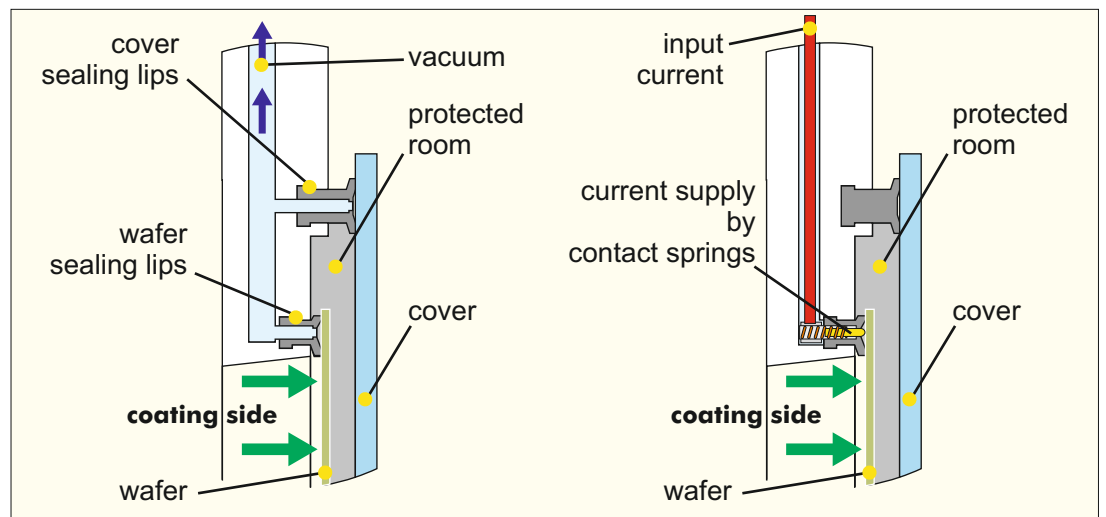
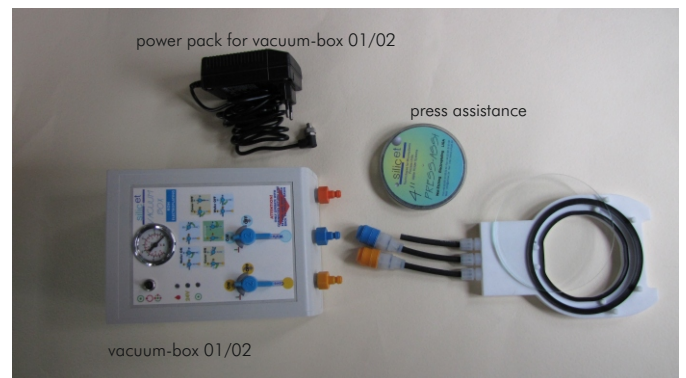
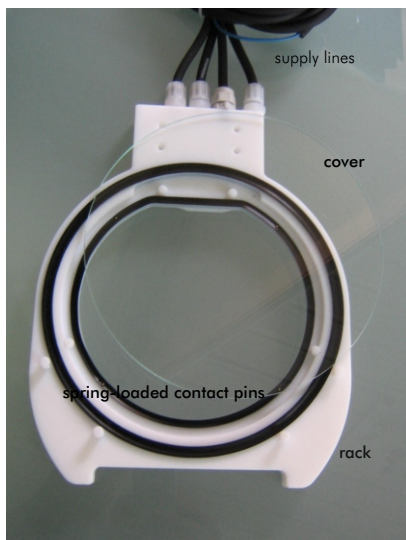
The wafers are held securely by means of a vacuum, thus also protecting them reliably from the electrolyte. The Wafer Holder PLUS G is equipped with an additional seal, which protects the entire wafer front including the edge from the electrolyte.

Wafer contact is made by four contact spring-loaded pins inside the sealing lips of the silicon wafer. (The number and location of the contact pins can be varied according to customer's requirements)

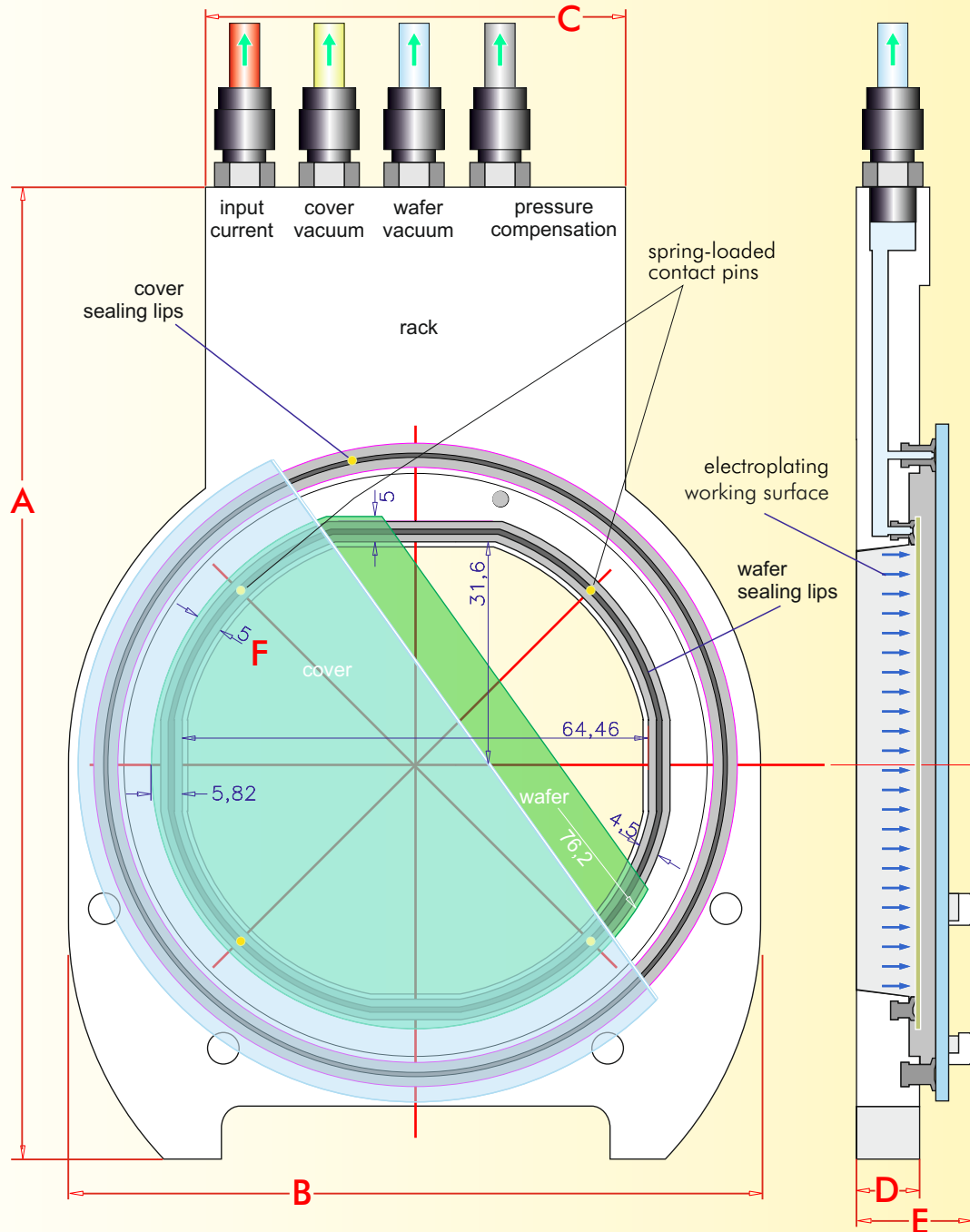
The protected area behind the wafer is ventilated to provide pressure compensation.

equipment: sealing lips:
supply lines:
rack:
cover:

EPDM/FPM peroxide cured and sulfure-free
4 Norprene / Viton-connecting tubes
PMMA / PTFE
glass / PMMA



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Dimension	Wafer	2"	3"	4"	5"	6"	8"
A - length		122 mm	145 mm	186 mm	239 mm	239 mm	313 mm
B - total width		80 mm	105 mm	132 mm	190 mm	190 mm	263 mm
C - width neck		80 mm	80 mm	80 mm	80 mm	84 mm	100 mm
D - thickness		12 mm	14 mm	14 mm	15 mm	15 mm	15 mm
E - compl. thickness		21 mm	22 mm	22 mm	22 mm	22 mm	24 mm
F - edge exclusion		5 mm	5 mm	5 mm	5 mm	5 mm	5 mm